Title (en)

DETECTING DEFECTS ON A WAFER

Title (de)

ERKENNUNG VON DEFEKTEN AUF EINEM WAFER

Title (fr)

DÉTECTION DES DÉFAUTS SUR UNE TRANCHE

Publication

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Application

EP 10741683 A 20100210

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Abstract (en)

[origin: WO2010093733A2] Methods and systems for detecting defects on a wafer are provided.

IPC 8 full level

H01L 21/66 (2006.01); **G01N 21/88** (2006.01); **G01N 21/95** (2006.01); **G01N 21/956** (2006.01)

CPC (source: EP KR)

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